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21st IEEE International Conference on Micro Electro Mechanical Systems

PROGRAM SCHEDULE

Sunday, January 13, 2008

- 4:00 p.m. – REGISTRATION
7:00 p.m.
- 6:30 p.m. WELCOME RECEPTION
8:30 p.m.

Monday, January 14, 2008

8:10 a.m. WELCOME ADDRESS

8:40 a.m. **INVITED SPEAKER**
CMOS BASED SENSORS: FROM A SAMPLE TO REAL PRODUCTS 1
 Felix Mayer
Sensirion Inc., SWITZERLAND

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Session Chairs:

H. Seidel, *Saarland University, GERMANY*

K. Turner, *University of California, Santa Barbara, USA*

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Georgia Institute of Technology, USA

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¹*University of Michigan, USA* and ²*University of California, Berkeley, USA*

10:00 a.m. EXHIBITON INSPECTION AND BREAK

Monday, January 14, 2008 (continued)

SESSION II - MICROFLUIDIC DEVICES & SYSTEMS

Session Chairs:

Y. Suzuki, *University of Tokyo, JAPAN*

J. Voldman, *Massachusetts Institute of Technology, USA*

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T. Ono, *Tohoku University, JAPAN*

L. Sarro, *Technical University Delft, THE NETHERLANDS*

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¹*Helsinki University of Technology, FINLAND and*
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¹*Universitat Autònoma de Barcelona, SPAIN and* ²*Centro Nacional Microelectronica, SPAIN*

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¹Stanford University, USA and ²Palo Alto Robert Bosch Research and Technology Center, USA
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W. Li¹, D.C. Rodger^{1,2} and Y.C. Tai¹
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P. Robert, *LETI, FRANCE*

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¹University of Freiburg, GERMANY and ²Fraunhofer Institute for Physical Measurement Technics, GERMANY
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Thursday, January 17, 2008

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10:00 a.m. EXHIBITON INSPECTION AND BREAK

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Y.-K. Kim, *Seoul National University, KOREA*

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¹*University of Michigan, USA*, ²*University of California, Berkeley* and
³*Arizona State University, USA*

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J.-U. Bu, *SenPlus, KOREA*

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¹*Interuniversity Microelectronics Center (IMEC), BELGIUM*,
²*Katholieke Universiteit Leuven, BELGIUM* and ³*ESA/ESTEC, THE NETHERLANDS*

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W - Wednesday, 1:30 pm. - 3:30 p.m.

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